

Substitute for form 1449A/PTO

**INFORMATION DISCLOSURE
STATEMENT BY APPLICANT**

(use as many sheets as necessary)

Sheet 1 of 3

Complete, if Known

Application Number 10/719858
 Filing Date 11-20-03
 First Named Inventor Miler, David
 Art Unit 2834
 Examiner Name T. Dougherty
 Attorney Docket Number 019930-002830

U.S. PATENT DOCUMENTS*

Examiner Initials*	Cite No. ¹	Document Number Number Kind Code ² (if known)	Publication Date MM-DD-YYYY	Name of Patentee or Applicant of Cited Document	Pages, Columns, Lines, Where Relevant Passages or Relevant Figures Appear	
TMD	AA	5,414,540	05/09/95	Patel et al.	359	39
TMD	AB	5,917,625	06/29/99	Ogusu et al.	359	130
TMD	AC	5,999,672	12/07/99	Hunter et al.	385	37
TMD	AD	6,028,689	02/22/00	Michalick et al.	359	224
TMD	AE	6,040,935	03/21/00	Michalick	359	198
TMD	AF	6,097,859	08/01/00	Solgaard	385	17
TMD	AG	6,108,471	08/22/00	Zhang et al.	385	37
TMD	AH	6,128,122	10/03/00	Drake et al.	359	224
TMD	AI	09/442,061	11/16/99	Weverka, et al.		
	AJ	US-				
	AK	US-				
	AL	US-				
	AM	US-				
	AN	US-				
	AO	US-				
	AP	US-				
	AQ	US-				
	AR	US-				
	AS	US-				
	AT	US-				

FOREIGN PATENT DOCUMENTS

Examiner Initials*	Cite No. ¹	Foreign Patent Document			Publication Date MM-DD-YYYY	Name of Patentee or Applicant of Cited Document	Pages, Columns, Lines, Where Relevant Passages or Relevant Figures Appear	T ⁴
		Country Code ³	Number ⁴	Kind Code ⁵ (if known)				
	AU							<input type="checkbox"/>
	AV							<input type="checkbox"/>
	AW							<input type="checkbox"/>
	AX							<input type="checkbox"/>
	AY							<input type="checkbox"/>
	AZ							<input type="checkbox"/>
	BA							<input type="checkbox"/>
	BB							<input type="checkbox"/>

Examiner
Signature*Thomas M. Dougherty*Date
Considered*12/1/03 and 10/29/04*

*EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609. Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant. ¹Applicant's unique citation designation number (optional). ²Kind Codes of U.S. Patent Documents at www.uspto.gov or MPEP 601.04. ³Enter Office that issued the document, by the two-letter code (WIPO Standard ST-3). ⁴For Japanese patent documents, the indication of the year of the reign of the Emperor must precede the serial number of the patent document. ⁵Kind of document by the appropriate symbols as indicated on the document under WIPO Standard ST-16 if possible. ⁶Applicant is to place a check mark here if English language Translation is attached.

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Substitute for form 1449B/PTO

**INFORMATION DISCLOSURE
STATEMENT BY APPLICANT**

(use as many sheets as necessary)

Sheet **2**

of

3**Complete If Known**

Application Number	Not Assigned 10/714858
Filing Date	Herewith 11-22-03
First Named Inventor	Miller, David
Art Unit	Not Yet Assigned 2634
Examiner Name	Not Yet Assigned T. DOUGHERTY
Attorney Docket Number	019930-002830

NON PATENT LITERATURE DOCUMENTS

Examiner Initials *	Cite No. ¹	Include name of the author (in CAPITAL LETTERS); title of the article (when appropriate); title of the item (book, magazine, journal, serial, symposium, catalog, etc.); date; page(s); volume-issue number(s); publisher, city and/or country where published.	T. ²
TMD	BC	T. Akiyama, et al.; "Controlled Stepwise Motion in Polysilicon Microstructures," Journal of Microelectromechanical Systems, Vol. 2, No. 3, September 1993, pp.106-110	
TMD	BD	Kenneth Bean, et al., "Anisotropic Etching of Silicon," IEEE Transactions on Electron Devices, Vol. Ed-25, No. 10, October 1978	
TMD	BE	Dino R. Ciarlo, "A latching accelerometer fabricated by the anisotropic etching of (110) oriented silicon wafers," Lawrence Livermore Nat'l Laboratory, March 1, 1992	
TMD	BF	A.S. Dewa, et al., "Development of a Silicon Two-Axis Micromirror for an Optical Cross-Connect," Solid State Sensors and Actuators Workshop, Hilton Head, South Carolina, pp. 93-96	
TMD	BG	Joseph Ford et al., "Wavelength Add Drop Switching Using Tilting Micromirrors," Journal of Lightwave Technology, Vol. 17, No. 5, May 1999	
TMD	BH	J. Grade et al., "A Large-Deflection Electrostatic Actuator for Optical Switching Applications, Solid-State Sensor and Actuator Workshop, Hilton Head Island, South Carolina, June 4-8, 2000; pp. 97-100	
TMD	BI	V. Kaajakari et al., "Ultrasonic Actuation for MEMS Dormancy-Related Stiction Reduction," In MEMS Reliability for Critical Applications, Proceedings of SAPIE Vol. 4180 (2000); pp. 60-65	
TMD	BJ	T.L. Koch et al., "Anisotropically etched deep gratings for InP/InGaAsP optical devices," J.App. Phys. 62 (8), 15 October 1987	
TMD	BK	I. Nishi et al., "Broad-Passband-Width Optical Filter for Multi-Demultiplexer Using a Diffraction Grating and a Retroreflector Prism," Electronics Letters, Vol. 21, No. 10, 9 th May 1985	
TMD	BL	P. Philippe et al., "Wavelength demultiplexer using echelette gratings on silicon substrate," Applied Optics, Vol. 24, No. 7, 1 April 1985	
TMD	BM	M. Schilling et al., "Deformation-free overgrowth of reactive ion beam etched submicron structures in InP by liquid phase epitaxy," Appl. Phys. Lett. 49 (12), 22 September 1986	
TMD	BH	Z. J. Sun et al., Demultiplexer with 120 channels and 0.29-nm Channel Spacing," IEEE Photonics Technology Letters, Vol. 10, No. 1, January 1998	
TMD	BO	W. Tang, et al., "Electrostatically Balanced Comb Drive for Controlled Levitation," Reprinted from Technical Digest IEEE Solid-State Sensor and Actuator Workshop, June 1990; pp. 198-202	
TMD	BP	L. Torcheux et al., "Electrochemical Coupling Effects on the Corrosion of Silicon Samples in HF Solutions," J. Electrochem Soc., Vol. 142, No. 6, June 1995	

Examiner
Signature*Thomas M. Dougherty*Date
Considered**2/1/03 and 10/29/04**

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Substitute for form 1449B/PTO		Complete if Known	
INFORMATION DISCLOSURE STATEMENT BY APPLICANT (use as many sheets as necessary)		Application Number	Non-Math Assigned N/119658
		Filing Date	Herewith 11-20-03
		First Named Inventor	Miller, David
		Art Unit	Non-Math Assigned 2634
		Examiner Name	Non-Math Assigned T. Dougherty
Sheet 3	of 3	Attorney Docket Number	019930-002830

NON-PATENT LITERATURE DOCUMENTS			
Examiner Initials *	Cite No. ¹	Include name of the author (in CAPITAL LETTERS); title of the article (when appropriate); title of the item (book, magazine, journal, serial, symposium, catalog, etc.); date; page(s); volume-issue number(s); publisher, city and/or country where published.	T ²
TMD		P. VanKessel et al., "A MEMS-Based Projection Display," Proceedings of the IEEE, Vol. 86, No. 8, August 1998; pp. 1687-1704	
TMD		Microfabricated Silicon High Aspect Ratio Flexures for In-Plane Motion; dissertation by C. Keller, Fall 1998	
TMD		Gimballed Electrostatic Microactuators with Embedded Interconnects; dissertation by L. Muller; Spring 2000	

Examiner Signature	Blawie M. Dougherty	Date Considered	12/1/03 and 10/29/04
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